

## B.Tech. DEGREE EXAMINATION, JULY 2022

Fourth Semester

## 18NTO308T - SMART SENSORS SYSTEMS

(For the candidates admitted during the academic year 2020 - 2021 & 2021 - 2022)

Note:

| Mote:       | _     |  | r - 20 - 20 - 20 - 20 - 20 - 20 - 20 - 2 | :: 5 -4 40 minutes and OMP shee      | t shoul | d be        | hand  | ded |
|-------------|-------|--|--|--------------------------------------|---------|-------------|-------|-----|
| (i)         | Par   | <b>t - A</b> should be answered in OMR shart to hall invigilator at the end of 40 <sup>th</sup> n  | neet w                                   | vithin first 40 minutes and OMR shee | t shoul | <b>u</b> 00 |       |     |
| (ii)        | Par   | t - B should be answered in answer be  | ooklet                                   | *•<br>•                              |         |             |       |     |
|             | 1/ TT | The control of the co |  |                                      | Max.    | Maı         | ks:   | 75  |
| Time: 2     | /2 H0 | urs  |  | ,                                    |         |             |       |     |
|             |       | $PART - A (25 \times 1 =$  | = 25 N                                   | Marks)                               | Marks   | BL          | CO    | PO  |
|             |       | Answer ALL Qu  |  |                                      |         |             |       |     |
| 1.          | Whi   | ch of the following error is cause   | d by                                     | a reversal of measured property?     | 1       | 1           | 1     | 1   |
|             |       | Hysteresis   | (B)                                      | Noise                                |         |             |       |     |
|             | (C)   | Digitization error   | DY                                       | Quantization error                   |         |             |       |     |
|             |       |  |  |                                      | 1       | 1           | 1     | 1   |
| 2.          |       | llest change which a sensor can d  |  |                                      | 1.0     | •           | -     |     |
|             |       | Accuracy   | ` '                                      | Scale                                |         |             |       |     |
|             | (C)   | Resolution   | (D)                                      | Precision                            |         |             |       |     |
| 2           | The   |  | <b>~</b> ~ ~ ~ ~                         | cording to                           | 1       | 1           | 1     | 1   |
| 3.          |       | rmocouple generates output volta<br>Circuit parameters   |  | Temperature                          |         |             |       |     |
|             | , ,   | Humidity   | '  | Voltage                              |         |             |       |     |
|             | (C)   | Trumdity   | (D)                                      | Voltage                              |         |             |       |     |
| 4.          |       | does not need any additional   | lene                                     | rgy source and directly generates    | 1       | 2           | 1     | 1   |
|             | an e  | lectric signal in response to an ex  | terna                                    | l stimulus.                          |         |             |       |     |
|             |       | Passive sensor   |  | Direct sensor                        |         |             |       |     |
|             |       | Active sensor  | (D)                                      | Indirect sensor                      |         |             |       |     |
|             |       |  |  |                                      | ,       | 2           | 1     | 1   |
| 5.          |       |  | a cry                                    | stalline material upon subjecting    | 1       | 2           | 1     | •   |
|             | it to | stress is  | (D)                                      | D 1 1                                |         |             |       |     |
|             |       | Magnetoresistive effect  | (B)                                      | Pyroelectric effect                  |         |             |       |     |
|             | (C)   | Thermoelectric effect  | (4)                                      | Piezoelectric effect                 |         | •           |       |     |
| 6           | Whi   | ch of the following material cann  | ot be                                    | used as hall effect sensors?         | 1       | 2           | 2     | 1   |
| 0.          | (A)   | Gallium Arsenide (GaAs)  | (B)                                      | Silicon dioxide                      |         |             |       |     |
|             | (C)   | Indium Antimonide (InSb)   | (D)                                      | Indium Arsenide (InAs)               |         |             |       |     |
|             | (0)   | maram rammerate ( )  | ( )                                      |                                      |         |             |       |     |
| 7.          | The   | typical velocities are for   | or lor                                   | ngitudinal waves and for             | . 1     | 1           | 2     | 1   |
|             |       | sverse waves.  |  |                                      |         |             |       |     |
|             | (A)   | 6000 m/s and 3000 m/s  | (B)                                      | 3000 m/s and 6000 m/s                |         |             |       |     |
|             | (C)   | 6000 m/min and 3000 m/min  | (D)                                      | 3000 m/min and 6000 m/min            |         |             |       |     |
|             |       | 1  | <b>b</b>                                 | ing a function of                    | . 1     | 3           | 2     | 1   |
| 8.          |       |  |  | eing a function of and the           | •       | ,           | -     | •   |
|             | acou  | stic wave velocity of the materia<br>Spacing between the electrode   | (R)                                      | Width of the device                  |         |             |       |     |
|             |       | Surface area   |  | Length of the electrode              |         |             |       |     |
| Page 1 of 4 | (C)   | Surface area   | (1)                                      | Longin of the electrode              | 16JA4/  | 18NT(       | 780EC |     |
|             |       |  |  |                                      |         |             |       |     |

|     |  | •.      | and thin insulating                | 1 | 2 | 2  | 1   |
|-----|--|---------|------------------------------------|---|---|----|-----|
| 9.  | TMR effect can be seen in multiple                                     |         |                                    |   |   |    |     |
|     | layer structures.  | (B)     | Antiferromagnetic alloy            |   |   |    |     |
|     | (A) Paramagnetic alloy   | (D)     | Diamagnetic alloy                  |   |   |    |     |
|     | (2) Ferromagnetic alloy  |         |                                    | , | 2 | 2  |     |
| 10  | In a magnetoresistive sensor, resista                                  | nce it  | ocreases with respect to magnetic  | 1 | 2 | 2  | 1   |
| 10. | field which is due to the magnetic field                               | ald for | rces electron to                   |   |   |    |     |
|     | (A) Take a longer path   | (B)     | Take a shorter path                |   |   |    |     |
|     | (C) Disappear  | (D)     | Random path                        |   |   |    |     |
|     |  |         |                                    | 1 | 1 | 3  | 1.2 |
| 11  | Which one if making IR detector bed                                    | come    | bulky, heavy and expensive?        | 1 | 1 | 3  | 1,3 |
|     | (A) Heat sink  | (BY     | Cooling system                     |   |   |    |     |
|     | (C) Power supply   | (D)     | Substrate                          |   |   |    |     |
|     | (e) is well supply   | (-)     |                                    | 1 | 2 | 3  | 1   |
| 12. | Which measurement is suitable for li                                   | iquid : | food samples?                      | 1 | 2 | 3  | 1   |
|     | (A) Transmission measurements  | (B)     | Reflectivity measurements          |   |   |    |     |
|     | (C) Scattering measurements  | (D)     | Absorption measurements            |   |   |    |     |
|     |  |         |                                    | 1 | 2 | 3  | 2   |
| 13. | The concentration of deoxygenated                                      | and     | oxygenated hemoglobin can be       | 1 | 2 | 5  | 2   |
|     | estimated through of fresh m   | eat.    | •                                  |   |   |    |     |
|     | (A) Blood density  | (B)     | Blood pH                           |   |   |    |     |
|     | (C) Blood color  | (D)     | Blood smell                        |   |   |    |     |
|     | 30   |         | . 11.1                             | 1 | 2 | 3  | 1   |
| 14. | Mainly, all light detectors are divide                                 | d into  | two major groups that are called   | • | - | _  | •   |
|     | ·  |         |                                    |   |   |    |     |
|     | (A) Magnetic and mechanical  | (B)     | Quantum and thermal                |   |   |    |     |
|     | (C) Electrical and optical   | (D)     | Electrical and mechanical          |   |   |    |     |
| 1.5 | 71.6   |         | istic releve flower and aroma in   | 1 | 1 | 3  | 1   |
| 15. | _  | aracte  | ristic colour, flavor and aroma in |   |   |    |     |
|     | wines.   | (D)     | Aldohyda compounds                 |   |   |    |     |
|     | <ul><li>(A) Alcohol compounds</li><li>(C) Phenolic compounds</li></ul> |         | Ketone compounds                   |   |   |    |     |
|     | (C) Frienone compounds   | (D)     | Retone compounds                   |   |   |    |     |
| 16  | A biosensor in general utilises a                                      |         | that senses the presence of an     | 1 | 1 | 4  | 1   |
| 10. | analyte.   |         | mat conses and processes of the    |   |   |    |     |
|     | (A) Chemical recognition element                                       | (B)     | Electrical recognition element     |   |   |    |     |
|     | (e) Biological recognition element                                     | (D)     | Thermal recognition element        |   |   |    |     |
|     |  |         | in it to be proceed as             |   |   |    |     |
| 17. | To measure the glucose in aqueous s                                    | olutio  | ns, which transducer can be used   | 1 | 3 | 4  | 1   |
|     | (A) Acoustic sensor  | (B)     | Temperature sensor                 |   |   |    |     |
|     | (C) Mass sensor  | (D)     | pH sensor                          |   |   |    |     |
|     |  |         |                                    | 1 | 1 |    |     |
| 18. | Which one is correct immobilization method?                            |         |                                    |   |   | 4  | 1   |
|     | (A) Heating  | 300     | Cross linking                      |   |   |    |     |
|     | (C) Diffusion  | (D)     | Dispersion                         |   |   |    |     |
|     |  | 41 4    |                                    |   |   | 90 |     |
| 19. | Enzymes are biological catalysts                                       | ınat    | promote the transformation of      | 1 | 1 | 4  | 1   |
|     | chemical species in  | (D)     | Inort quatoms                      |   |   |    |     |
|     | <ul><li>(A) Ambient systems</li><li>(C) Vacuum systems</li></ul>       |         | Inert systems Living systems       |   |   |    |     |
|     | TUT VACUUM SYSTEMS   | (10)    | TIAME SASICINS                     |   |   |    |     |

| 20.                          | The microcontroller is used to measure the  (A) Amplitude modulated signal (B) Period  (C) Phase modulated signal (D) Intensit   | modulated signal  | 1              | Z       | 7         | ,         |
|------------------------------|--|---|----------------|---------|-----------|-----------|
| 21.                          | Which of the following is the best method for photo (A) Electroplating method (B) Sputter (C) Spin coater (D) Therma   |   | . 1            | 1       | 5         | 1         |
| 22.                          | Plasma etching process is often referred as  (A) Wet etching (C) Chemical etching (D) Anisotr  | hing<br>ropic wet etching   | 1              | 1       | 5         | 1         |
| 23.                          | The process of planting atoms in to host semicon change the electrical characteristics of the host material (A) Adding process (B) Sinterial (C) Etching process (D) Doping  | terials is called ng process  | 1              | 2       | 5         | 1         |
| 24.                          | For which layer deposition, electroplating met process.  (A) Seed layer  (B) Structu  (C) Sacrificial layer  (D) Buffer  | ral layer   | 1              | 1       | 5         | 1         |
| 25.                          | Which of the following one belongs to nanomateris (A) Silicon (B) Gold   | al category   | 1              | 1       | 5         | 1         |
| 7                            | (C) Graphene (D) German  | nium  |                |         |           |           |
| ,                            |  | nium  | Marks          | BL      | со        | ро        |
| 26. a.                       | (C) Graphene (D) German $PART - B (5 \times 10 = 50 \text{ Marks})$  |   | Marks          | BL<br>2 | <b>co</b> | <b>PO</b> |
|                              | PART – B (5 × 10 = 50 Marks) Answer ALL Questions  | letail.   |                | 2       |           |           |
| b.                           | PART – B (5 × 10 = 50 Marks) Answer ALL Questions  Write any five static characteristics of a sensor in d  (OR)  | letail.   | 10             | 2       | 1         | 1         |
| b.<br>27. a.                 | PART – B (5 × 10 = 50 Marks)  Answer ALL Questions  Write any five static characteristics of a sensor in d  (OR)  Explain piezoelectric effect and pyroelectric effect.  Describe in detail about the surface acoustic way   | letail. ves (SAW) principle and   | 10             | 2       | 1 2       | 1         |
| b.<br>27. a.<br>b.           | PART – B (5 × 10 = 50 Marks) Answer ALL Questions  Write any five static characteristics of a sensor in d  (OR)  Explain piezoelectric effect and pyroelectric effect.  Describe in detail about the surface acoustic way working of a saw sensor.  (OR)   | letail.  ves (SAW) principle and magnetic transistors.                        | 10<br>10<br>10 | 2 2     | 1 2       | 1 1,3     |
| b.<br>27. a.<br>b.<br>28. a. | PART – B (5 × 10 = 50 Marks) Answer ALL Questions  Write any five static characteristics of a sensor in d  (OR)  Explain piezoelectric effect and pyroelectric effect.  Describe in detail about the surface acoustic way working of a saw sensor.  (OR)  Explain the construction and working principle of the Discuss the basics of visible light colour set | detail.  ves (SAW) principle and magnetic transistors.  ensor and high energy | 10<br>10<br>10 | 2 2 1   | 1 2 2     | 1 1,3     |

(OR)

- Explain any two biosensors based on bioreceptors with their working 10 2 4 principles.
- 30. a. Describe the high aspect ratio LIGA process used for microsystem 10 2 6 to components in detail with next schematics.
  - b. Explain about the creation of clusters and manscrystalline materials. 10 2 8

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